Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Previously Presented) A high yield fixture for the production of demultiplexer filters for dense wavelength division multiplexers, the fixture comprising:

a disk with a concentric aperture , the disk adapted to be rotatable at greater than 2400 rpm during operation;

a dedicated multi-crystal quartz crystal thickness monitor positioned within the concentric aperture;

an optical thickness monitor;

a clam shell shutter;

a magnetic induction rotation mechanism; and,

multiple substrates rigidly attached to the disk and arranged radially about the concentric aperture containing the quartz crystal monitor.

2. (Previously Presented) A high yield fixture for production of optical filters, the fixture comprising:

a rotating disk with a concentric aperture;

a thickness monitor arranged within said aperture;

a shuttering means for shuttering the disk;

at least one substrate; said substrate rigidly attached to the disk and,

rotating means for rotating the fixture.

3. (Previously Presented) The fixture of claim 2, wherein the disk is adapted to be rotated at greater than 500 rpm.

4. (Original) The fixture of claim 3, wherein the thickness monitor is a dedicated quartz crystal monitor.

5. (Original) The fixture of claim 4, wherein the shuttering means is a clam shell shutter.

6. (Previously Presented) The fixture of claim 5, wherein the fixture further comprises:

multiple substrates rigidly attached to the disk and arranged radially about the concentric aperture.

7. (Canceled).

8. (Previously Presented) The fixture of claim 2, wherein the rotating means is a magnetic induction rotation mechanism.

9. (Canceled) .

10. (Previously Presented) A high speed substrate assembly for use in a line-of-sight deposition process, the assembly comprising:

multiple independent fixtures,

the fixtures comprising:

a rotating disk with a concentric aperture;

at least one thickness monitor arranged within said concentric aperture;

at least one substrate; said substrate rigidly attached to the disk;

shuttering means for shuttering the fixture; and, rotating means for rotating the disk.

11. (Currently Amended) The assembly of claim 10, wherein the at least one thickness monitor further comprises:

a dedicated quartz crystal monitor~~; and,~~

~~an optical thickness monitor~~.

12. (Cancelled).

13. (Currently Amended) The assembly of claim 11, wherein the at least one substrate is multiple substrates, the substrates being located about the concentric aperture and around the quartz crystal monitor.

14. (Original) The assembly of claim 13, wherein the shuttering means is a clam shell shutter.

15. (Original) The assembly of claim 14, wherein the rotating means is a magnetic induction rotation mechanism.

16.-20. (Canceled)